
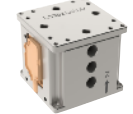

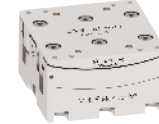








Table 1 - Piezoelectric Motion Units - "Lab" Series Products

	Linear Motion Unit		Rotary Motion Unit		
	X direction, Motion Stag	Z direction, Motion Stage	Tx, Tilting Stage		Tz, Rotary Stage
35 mm	 LS35x.Lab.O/.E Sereis Options: .NM / .HV/ .UHV	 LS35z.Lab.O Sereis Options: .NM / .HV/ .UHV	 GS35-35.Lab.O Sereis Options: .NM / .HV/ .UHV	 GS35-55.Lab.O Sereis Options: .NM / .HV/ .UHV	 RS35.Lab.O/.E Sereis Options: .NM / .HV/ .UHV
65 mm	 LS65x.Lab.O/.E Sereis Options: .NM / .HV / .UHV	 LS65z.Lab.O Sereis Options: .NM / .HV / .UHV	 GS65-77.Lab.O Sereis Options: .NM / .HV / .UHV	 GS65-97.Lab.O Sereis Options: .NM / .HV / .UHV	 RS65.Lab.O/.E Sereis Options: .NM / .HV / .UHV

.NM, non-magnetic; .HV, high vacuum compatible; .UHV, ultra-high vacuum compatible

Optional models ⇔

- .E ~ 100 nm Optic Encoder
- .O ~ 2nm Optic Encoder
- .adv ~ 0.5 nm Optic Encoder

- .HV ~ 1e-7 mbar high vacuum compatible
- .UHV ~ 2e-11 mbar ultra-high vacuum compatible

.NM ~ non-magnetic

"LS35x.Lab" Sereis

- LS35x.Lab.E
- LS35x.Lab.O
- LS35x.Lab.O.HV
- LS35x.Lab.O.UHV
- LS35x.Lab.O.NM
- LS35x.Lab.O.HV.NM
- LS35x.Lab.O.UHV.NM
- LS35x.Lab.adv
- LS35x.Lab.adv.HV
- LS35x.Lab.adv.UHV
- LS35x.Lab.adv.NM
- LS35x.Lab.adv.HV.NM
- LS35x.Lab.adv.UHV.NM

LS35z.Lab Sereis

- LS35z.Lab.O
- LS35z.Lab.O.HV
- LS35z.Lab.O.UHV
- LS35z.Lab.O.NM
- LS35z.Lab.O.HV.NM
- LS35z.Lab.O.UHV.NM
- LS35z.Lab.adv
- LS35z.Lab.adv.HV
- LS35z.Lab.adv.UHV
- LS35z.Lab.adv.NM
- LS35z.Lab.adv.HV.NM
- LS35z.Lab.adv.UHV.NM

LS65x.Lab Sereis

- LS65x.Lab.E
- LS65x.Lab.O
- LS65x.Lab.O.HV
- LS65x.Lab.O.UHV
- LS65x.Lab.O.NM
- LS65x.Lab.O.HV.NM
- LS65x.Lab.O.UHV.NM
- LS65x.Lab.adv
- LS65x.Lab.adv.HV
- LS65x.Lab.adv.UHV
- LS65x.Lab.adv.NM
- LS65x.Lab.adv.HV.NM
- LS65x.Lab.adv.UHV.NM

LS65z.Lab Sereis

- LS65z.Lab.O
- LS65z.Lab.O.HV
- LS65z.Lab.O.UHV
- LS65z.Lab.O.NM
- LS65z.Lab.O.HV.NM
- LS65z.Lab.O.UHV.NM
- LS65z.Lab.O.LR
- LS65z.Lab.O.LR.HV
- LS65z.Lab.O.LR.UHV
- LS65z.Lab.O.LR.NM
- LS65z.Lab.O.LR.HV.NM
- LS65z.Lab.O.LR.UHV.NM
- LS65z.Lab.adv
- LS65z.Lab.adv.LR
- LS65z.Lab.adv.LR.HV
- LS65z.Lab.adv.LR.UHV
- LS65z.Lab.adv.LR.NM
- LS65z.Lab.adv.LR.HV.NM
- LS65z.Lab.adv.LR.UHV.NM

RS35.Lab Sereis

- RS35.Lab.E
- RS35.Lab.O
- RS35.Lab.O.HV
- RS35.Lab.O.UHV
- RS35.Lab.O.NM
- RS35.Lab.O.HV.NM
- RS35.Lab.O.UHV.NM
- RS65.Lab.E
- RS65.Lab.O
- RS65.Lab.O.HV
- RS65.Lab.O.UHV
- RS65.Lab.O.NM
- RS65.Lab.O.HV.NM
- RS65.Lab.O.UHV.NM

GS35-35.Lab.O Sereis

- GS35-35.Lab.O
- GS35-35.Lab.O.HV
- GS35-35.Lab.O.UHV
- GS35-35.Lab.O.NM
- GS35-35.Lab.O.HV.NM
- GS35-35.Lab.O.UHV.NM

GS35-55.Lab.O Sereis

- GS35-55.Lab.O
- GS35-55.Lab.O.HV
- GS35-55.Lab.O.UHV
- GS35-55.Lab.O.NM
- GS35-55.Lab.O.HV.NM
- GS35-55.Lab.O.UHV.NM

GS65-77.Lab.O Sereis

- GS65-77.Lab.O
- GS65-77.Lab.O.HV
- GS65-77.Lab.O.UHV
- GS65-77.Lab.O.NM
- GS65-77.Lab.O.HV.NM
- GS65-77.Lab.O.UHV.NM

GS65-97.Lab.O Sereis

- GS65-97.Lab.O
- GS65-97.Lab.O.HV
- GS65-97.Lab.O.UHV
- GS65-97.Lab.O.NM
- GS65-97.Lab.O.HV.NM
- GS65-97.Lab.O.UHV.NM

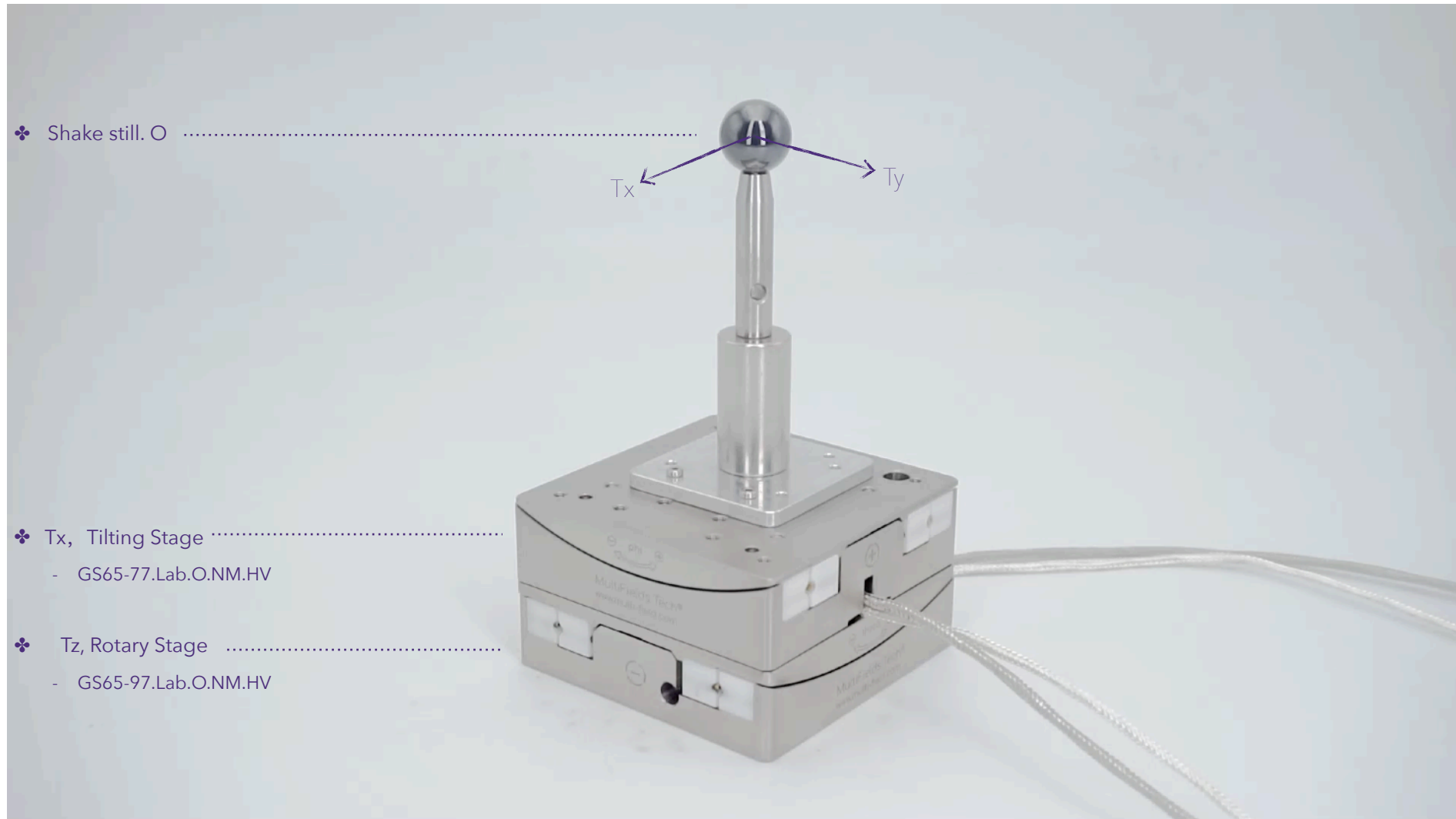
Piezoelectric Motion - RT

Piezoelectric Motion - RT

"GS65" Goniometer Stage - Introduction to physical application

Introduction to physical application

Physical motion demonstration: high vacuum & completely non-magnetic solution, 2 degrees of freedom swing motion



压电·摇摆位移台- GS35-35.Lab.O (闭环)

室温·压电运动解决方案 - “Lab 系列” 良好封装的摇摆位移台

外形紧凑，动力性能不折扣的摇摆位移台；



GS35-35.Lab.O

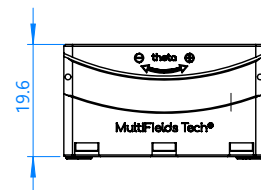
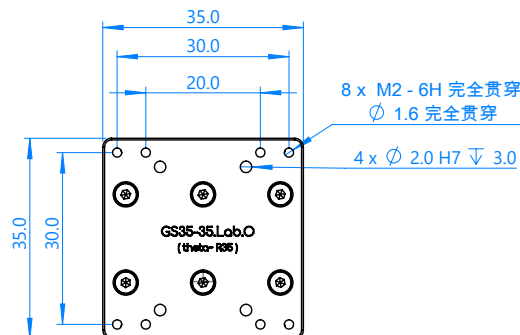
Features

- Very Quiet, 20 kHz drive frequency
- Compact Design, 35 mm x 35 mm x 20 mm
- 闭环控制 · 空间传感分辨率(O) 0.06urad(默认), 0.03urad可选
- Min step below 1 urad
- 可提供多轴堆叠安装转接件
- Controller compatible with linear and rotary stage
- Support Options, high vacuum (.HV) & ultra- high vacuum (.UHV)

Optional models

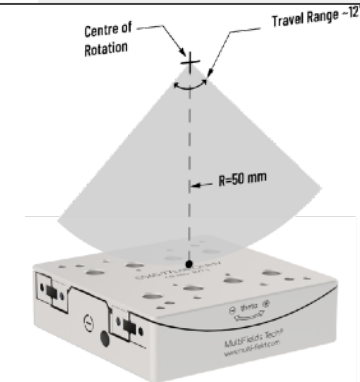
- .O ~ 2nm Optic Encoder .HV ~ 1e-7 mbar high vacuum .UHV ~ 2e-11 mbar ultra- high vacuum .NM ~ non-magnetic
- GS35-35.Lab.O
 - GS35-35.Lab.O.HV
 - GS35-35.Lab.O.UHV
 - GS35-35.Lab.O.NM
 - GS35-35.Lab.O.NM.HV
 - GS35-35.Lab.O.NM. UHV

2D·Drawings



GS35-35.Lab Series – Specification

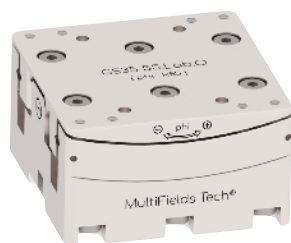
Optional Versions ⇨	GS35-35.Lab.O
Special version is optional ⇨	.NM, non-magnetic; .HV, high vacuum compatible; .UHV, ultra-high vacuum compatible;
1 Dimension	35 mm × 35 mm × 20 mm
2 Main Material	标准版 .HV, .UHV Stainless; .NM, 纯钛
3 Mass	250 g
4 Travel Range	+/- 10 °
5 Drive Frequency	Max. 20 kHz (very quiet)
6 Open loop · spatial motion resolution	0.5 urad
7 Cable & Connectors	默认, 屏蔽线缆 D-Sub15 .UHV 版本, kapton漆包线, PEEK D-Sub 15
Motion parameters for recommended installation I	
6 Tilting radius	35 mm
7 Velocity	~ 3 °/s (max)*
8 Mini Step Size	2 urad
10 Load	2 kg
11 Holding Torque	25 N*mm
12 Driving Torque	10 N*mm
Sensor	
13 Sensor Type	Optic Encoder (.O)
14 Sensor Range	20 °
15 Sensor Resolution	1 urad



压电·摇摆位移台- GS35-55.Lab.O (闭环)

室温·压电运动解决方案 – “Lab 系列” 良好封装的摇摆位移台

外形紧凑，动力性能不折扣的压电摇摆位移台；



GS35-55.Lab.O

Features

- Very Quiet, 20 kHz drive frequency
- Compact Design, 35 mm x 35 mm x 20 mm
- 闭环控制 · 空间传感分辨率(.O) 0.05urad(默认), 0.02urad可选
- Min step below 1 urad
- 可提供多轴堆叠安装转接件
- Controller compatible with linear and rotary stage
- Support Options, high vacuum (.HV) & ultra- high vacuum (.UHV)

Optional models

.O ~ 2nm Optic Encoder

- GS35-55.Lab.O
- GS35-55.Lab.O.HV.NM

.HV ~ 1e-7 mbar high vacuum

- GS35-55.Lab.O.HV
- GS35-55.Lab.O.UHV.NM

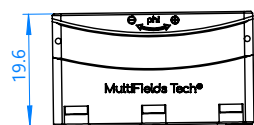
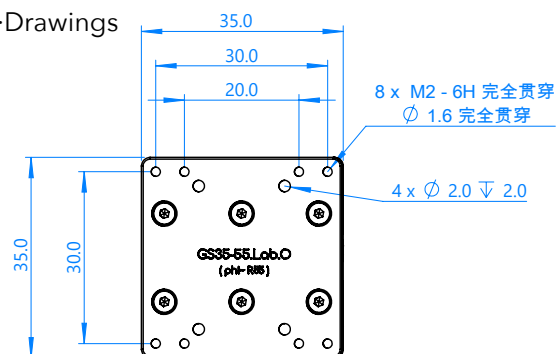
.UHV ~ 2e-11 mbar ultra- high vacuum

- GS35-55.Lab.O.UHV

.NM ~ non-magnetic

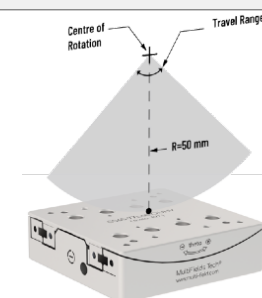
- GS35-55.Lab.O.NM

2D·Drawings



GS35-55.Lab Series – Specification

Optional Versions ⇄	GS35-55.Lab.O
Special version is optional ⇄	.NM, non-magnetic; .HV, high vacuum compatible; .UHV, ultra-high vacuum compatible;
1 Dimension	35 × 35 mm × 20 mm
2 Main Material	标准版 .HV, .UHV, Stainless; .NM, 纯钛
3 Mass	250 g
4 Travel Range	+/- 10°
5 Drive Frequency	Max. 20 kHz (very quiet)
6 Open loop · spatial motion resolution	0.5 urad
7 Cable & Connectors	默认, 屏蔽线缆 D-Sub15 .UHV 版本, kapton漆包线, PEEK D-Sub15
Motion parameters for recommended installation I	
8 Tilting radius	55 mm
9 Velocity	~ 3°/s*
10 Mini Step Size	2 urad
11 Load	2 kg
12 Holding Torque	25 N*mm
13 Driving Torque	10 N*mm
Sensor	
14 Sensor Type	Optic Encoder (.O)
15 Sensor Range	20°
16 Sensor Resolution	1 urad



Goniometer Stage - GS65-77.Lab.O

Tilting motion with R=77 mm, compatible with GS65-77.Lab.O stage



GS65-77.Lab.O

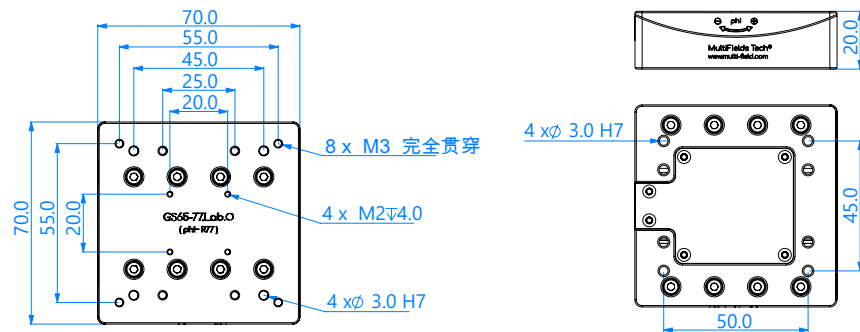
Features

- Very Quiet, 20 kHz drive frequency
- Compact Design, 70 × 70 mm × 20 mm
- Min step below 1 urad
- Multi-axis stacking adapters available
- Controller compatible with linear and rotary stage
- Support Options, high vacuum (.HV) & ultra- high vacuum (.UHV)

Optional models

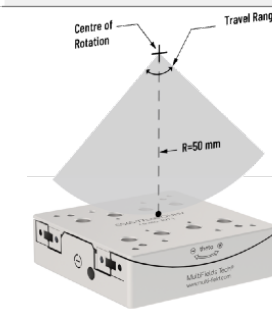
- .O ~ 2nm Optic Encoder .HV ~ 1e-7 mbar high vacuum .UHV ~ 2e-11 mbar ultra- high vacuum .NM ~ non-magnetic
- GS65-77.Lab.O
 - GS65-77.Lab.O.HV
 - GS65-77.Lab.O.UHV
 - GS65-77.Lab.O.NM
 - GS65-77.Lab.O.HV.NM
 - GS65-77.Lab.O.UHV.NM

2D-Drawings



GS65-77.Lab Series – Specification

Optional Versions ⇨	GS65-77.Lab.O
Special version is optional ⇨	.NM, non-magnetic; .HV, high vacuum compatible; .UHV, ultra-high vacuum compatible;
1 Dimension	70 × 70 mm × 20 mm
2 Main Material	标准版 .HV .UHV Aluminium; .NM 纯Ti
3 Mass	650 g
4 Travel Range	+/- 10°
5 Drive Frequency	Max. 20 kHz (very quiet)
6 Open loop · spatial motion resolution	0.2 urad
7 Cable & Connectors	默认, 屏蔽线缆 D-Sub15 .UHV 版本, kapton漆包线, PEEK D-Sub15
Motion parameters for recommended installation I	
6 Tilting radius	77 mm
7 Velocity	~ 3°/s*
8 Mini Step Size	1 urad
10 Load	2 kg
11 Holding Torque	50 N*mm
12 Driving Torque	20 N*mm
Sensor	
13 Sensor Type	Optic Encoder (.O)
14 Sensor Range	20°
15 Sensor Resolution	0.06urad(default), 0.03urad optional



Goniometer Stage - GS65-97.Lab.O

Tilting motion with R=97 mm, compatible with GS65-97.Lab.O stage



GS65-97.Lab.O

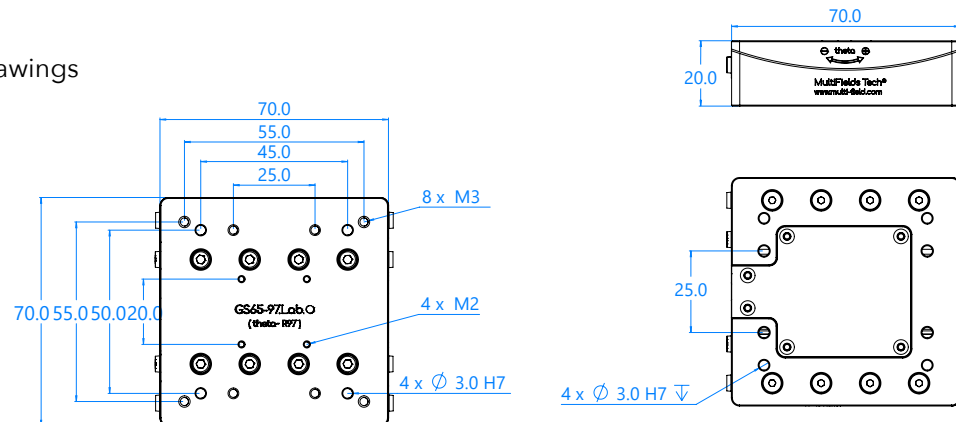
Features

- Very Quiet, 20 kHz drive frequency
- Compact Design, 70 × 70 mm × 20 mm
- Min step below 1 urad
- Multi-axis stacking adapters available
- Controller compatible with linear and rotary stage
- Support Options, high vacuum (.HV) & ultra- high vacuum (.UHV)

Optional models

- .O ~ 2nm Optic Encoder .HV ~ 1e-7 mbar high vacuum .UHV ~ 2e-11 mbar ultra- high vacuum .NM ~ non-magnetic
- GS65-97.Lab.O
 - GS65-97.Lab.O.HV
 - GS65-97.Lab.O.UHV
 - GS65-97.Lab.O.NM
 - GS65-97.Lab.O.HV.NM
 - GS65-97.Lab.O.UHV.NM

2D-Drawings



GS65-97.Lab Series – Specification

Optional Versions ⇨	GS65-97.Lab.O
Special version is optional ⇨	.NM, non-magnetic; .HV, high vacuum compatible; .UHV, ultra-high vacuum compatible;
1 Dimension	70 × 70 mm × 20 mm
2 Main Material	标准版 .HV .UHV Aluminium; .NM 纯Ti
3 Mass	650 g
4 Travel Range	+/- 10°
5 Drive Frequency	Max. 20 kHz (very quiet)
6 Open loop · spatial motion resolution	0.2 urad
7 Cable & Connectors	默认, 屏蔽线缆 D-Sub15 .UHV 版本, kapton漆包线, PEEK D-Sub15
Motion parameters for recommended installation I	
8 Tilting radius	97 mm
9 Velocity	~ 3°/s*
10 Mini Step Size	1 urad
11 Load	2 kg
12 Holding Torque	50 N*mm
13 Driving Torque	20 N*mm
Sensor	
14 Sensor Type	Optic Encoder (.O)
15 Sensor Range	20°
16 Sensor Resolution	0.05urad(default), 0.02urad optional

